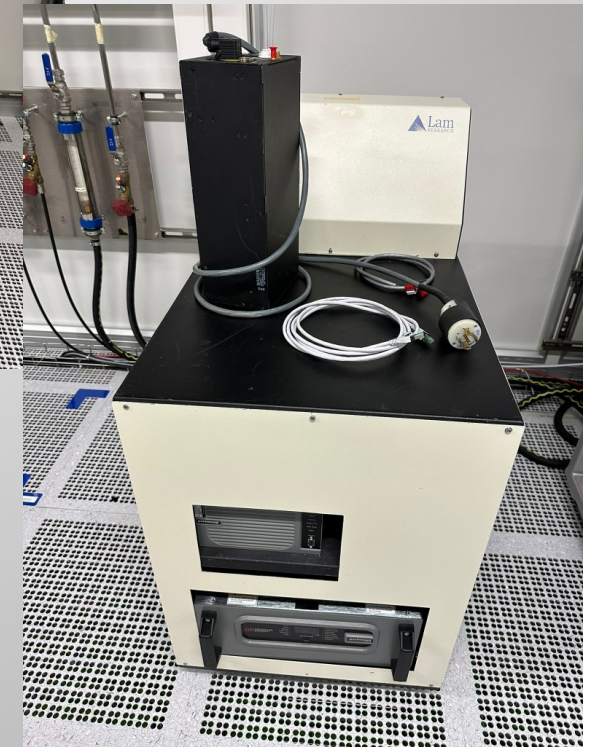




LAM Research
4528i Oxide Etch 200mm Configuration
SN 24041

LAM Research
4520i Oxide Etch SN 24041



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LAM Research 4528i Oxide Etch SN 24041



Tool Model : 4528i
Tool Serial Number : 24041
Bulkhead system mount w/tunnel covers
Hine 38A open cassette Send/Receive indexers
Software Version: Envision 1.5.2
Oxide etcher, 8"
Clamp type, ESC
RF power Rack ENI Paramount 1213 Paramount MF 3KW
AE Isotropic Module
Chiller Unit (LAM 2080)
AC Rack AC Power Distribution
Moving gap
Back Helium Colling
Main Power 208V, 3 Phase, 5Wire, 175A, 60/
Belt driven load station
Standard load station shuttle spatula
Upper chamber gap drive encoder
Dip PCB for RF power tuning
Aluminum upper chamber electrode

Single lower chamber endpoint detector (405/520nm) Non-
-heated endpoint window
Low pressure chamber manifold
HPS valve for chamber isolation
AC--2 chamber pressure control
Lower chamber RGA port
8 -- Gas box Orbital gas box
Gas 1: AR 500 sccm
Gas 2: CF4 200 sccm
Gas 3: CHF3 100 sccm
Gas 4: SF6 100 sccm
Gas 5: N2 100 sccm
Gas 6: H2 1000 sccm
Gas 7 NF3 1000 sccm
Gas 1-: O2 100sccm
UPC: He (50 sccm)
AC input box for AC power inlet
Trip breakers AC/DC power box

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- **Equipment Support**
PM, CM, Trouble shooting, Upgrading, Training and Onsite Service Contracts
- **Process Support**
Process design, Improvement, Fab-to-Fab Transfer and Integration
- **Refurbishment**
From custom to complete refurbishment
- **Relocation**
Auditing, Fingerprinting, Decommissioning, Installation, Acceptance
- **Materials**
Supplier of first class second source materials

